

# Weining Liu

## List of Publications by Year in descending order

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8  
papers

22  
citations

2258059

3  
h-index

2053705

5  
g-index

8  
all docs

8  
docs citations

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times ranked

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citing authors

#	ARTICLE	IF	CITATIONS
1	High quality of N-polar GaN film fabricated by layer transfer technology using high selective material removal rate of CMP. <i>Materials Science in Semiconductor Processing</i> , 2022, 141, 106440.	4.0	2
2	Implementation of Recessed Gate Normally off GaN Metal-Insulator-Semiconductor High Electron Mobility Transistors by Electrodeless Photoelectrochemical Etching. <i>ACS Applied Electronic Materials</i> , 2022, 4, 897-902.	4.3	1
3	2.0 kV/2.1 mÅcm <sup>2</sup> Lateral p-GaN/AlGaIn/GaN Hybrid Anode Diodes With Hydrogen Plasma Treatment. <i>IEEE Electron Device Letters</i> , 2022, 43, 693-696.	3.9	7
4	Effects of the stepped sidewall morphology on the ON-state performance for vertical GaN trench-gate MOSFETs. <i>Applied Physics Express</i> , 2022, 15, 076502.	2.4	5
5	Simulation of enhancement-mode recessed-gate p-channel HFETs based on polarization-induced doping and an InGaIn/GaN/AlGaIn heterostructure. <i>Semiconductor Science and Technology</i> , 2021, 36, 07LT01.	2.0	1
6	Dual Current and Voltage Sensitivity Temperature Sensor Based on Lateral p-GaN/AlGaIn/GaN Hybrid Anode Diode. <i>IEEE Sensors Journal</i> , 2021, 21, 22459-22463.	4.7	6
7	Fabrication of enhancement-mode high electron mobility transistors (HEMTs) by electrodeless photoelectrochemical etching. , 2021, , .		0
8	Suppression of Mg Propagate into Subsequent Layers by Furnace Annealing. , 2021, , .		0